



# Japan EHS Committee Meeting Summary and Minutes

# **SEMICON Japan 2012**

Friday, December 7, 2012, 10:00-12:30 Makuhari Messe, Chiba, Japan

### **Next Committee Meeting**

SEMI Japan Standards Spring 2013 Meetings Thursday, April 18, 2013, 10:00-17:00 SEMI Japan, Tokyo, Japan

## **Table 1 Meeting Attendees**

Co-Chairs: Supika Mashiro (Tokyo Electron), Hidetoshi Sakura (Intel), Moray Crawford (Hatsuta Seisakusho)

SEMI Staff: Naoko Tejima (SEMI Japan)

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Company	Last	First	Company	Last	First
Hatsuta Seisakusho	Crawford	Moray	Dainippon Screen Manufacturing	Nishiguchi	Naokatsu
Salus Engineering International	Evanston	Chris	Safe Techno	Nogawa	Kaoru
Murata Machinery	Goto	Ikuo	Intel	Sakura	Hidetoshi
TÜV Rheinland Japan	Hamano Yuji TÜV SÜD Japa		TÜV SÜD Japan	Sekiguchi	Yuichi
Tokyo Electron	Hoshi	Geroge	Hatsuta Seisakusho	Suenaga	Yukiko
Horiba	Ibuka	Shigehito	TÜV Rheinland Japan	Sugita	Yoshihiro
Tokyo Electron	Mashiro	Supika	Dainippon Screen Manufacturing	Takasaki	Yoshihisa
Murata Machinery	Nakashima	Norio	SEMI Japan	Tejima	Naoko
SOKUDO	Nakatani	Eiji			

<sup>\*</sup> alphabetical order by last name

# **Table 2 Leadership Changes**

None

# **Table 3 Ballot Results**

None

## **Table 4 Authorized Ballots**

#	When	SC/TF/WG	Details
			Revision to SEMI S23-0311, Guide for Conservation of Energy, Utilities and Materials Used by Semiconductor Manufacturing Equipment





### **Table 5 Authorized Activities**

Document #	Туре	SC/TF/WG	Details
			Line Item Revisions to SEMI S2-0712, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment Revisions Related to
		Force	Section 19 Seismic Protection

Note: SNARFs and TFOFs are available for review on the SEMI Web site at:

http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF

#### **Table 6 New Action Items**

Item #	Assigned to	Details
	SEMI Staff	To request Europe EHS Committee to provide a liaison repot every time they have a meeting.
EHS121207-02	S23 Revision Task Force	To submit Doc.#5513 for the earliest possible cycle.

#### 1 Welcome, Reminders, and Introductions

Moray Crawford, committee co-chair, called the meeting to order at 10:00. Self-introductions were made followed by the agenda review.

#### 2 Technical Committee Award

Technical Committee Awards were given to the below member to appreciate his outstanding efforts and leadership.

• Eiji Nakatani (Sokudo) – Seismic Protection Task Force activities

# 3 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

# 4 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on September 25, 2012.

**Motion:** To approve the minutes of the previous meeting as submitted.

By / 2<sup>nd</sup>: Shigehito Ibuka (Horiba) / Naokatsu Nishiguchi (Dainippon Screen Manufacturing)

**Discussion:** None.

Vote: 15 in favor and 0 opposed. Motion passed.

Attachment: 01\_JA\_EHS\_Previous\_Mtg\_Minutes\_121207

# 5 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2012-2013 Calendar of Events, SEMICON Japan 2012, 2012 Standards Awards, 2013 Critical Dates for SEMI Standards Ballots, Regulation SC Report, A&R SC Report, SEMI Standards Publication, New Standards Ballot and Membership Systems, New Ballot Formatting Templates, Style Manual and Compilation of Terms and Contact Information.

Attachment: 02\_SEMI\_Staff\_Report\_121207





#### 6 Liaison Reports

#### 6.1 Japan Regional Standards Committee (JRSC)

Hidetoshi Sakura reported for the Japan Regional Standards Committee (JRSC) that there were no particular things should be reported.

#### 6.2 Global Coordinating Subcommittee (GCS)

Hidetoshi Sakura reported for the Global Coordinating Subcommittee (GCS) that GCS meetings and approvals have not been made in between today from the previous committee meeting.

#### 6.3 North America EHS Committee

Paul Trio reported for the North America EHS Committee. This report included Task Force and Leadership Changes, Leadership, Current Committee Organization Chart, Meeting Information, Publication information, Document Review Summary of NA Fall 2012 Meetings, Ballots to be Reviewed at NA Spring 2013 Meetings, Subcommittees & Task Forces Reports, NA Spring EHS Meetings Schedule.

**Attachment:** 03\_NA\_EHS\_Report\_December2012\_121207

6.4 Europe EHS Committee

No report was provided.

Supika Mashiro requested that SEMI Europe EHS committee should submit the liaison report, if they had a meeting.

**Action Item:** SEMI staff to request Europe EHS Committee to provide a liaison repot every time they have a meeting.

6.5 Taiwan EHS Committee

No report was provided.

6.6 Korea EHS Working Group

No Report was provided.

## 7 Subcommittee & Task Force Reports

## 7.1 S13 Revision Task Force

Shigehito Ibuka reported for the S13 Revision Task Force. Of note:

• Doc.#4976C, Revision to SEMI S13-0305, Environmental, Health and Safety Guideline for Documents Provided to the Equipment User for Use with Semiconductor Manufacturing Equipment with Title Change to: Environmental, Health and Safety Guideline for Documents Provided to the Equipment User for Use with Manufacturing Equipment is under review at the A&R Sub Committee. After it passes the A&R SC review, Task Force will implement the proof signature for the publication.

# 7.2 S17 Revision Task Force

Norio Nakashima reported for the S17 Revision Task Force. Of note:

• Doc.#5353, Line Item Revision to SEMI S17-0311, Safety Guideline for Unmanned Transport Vehicle (UTV) System is under review at the A&R Sub Committee. The Task Force is waiting the result of the A&R SC review.

### 7.3 S18 Revision Task Force

Supika Mashiro reported for the S18 Revision Task Force that there were not particular activities.





#### 7.4 S23 Revision Task Force

George Hoshi reported on progress for the S23 Revision Task Force. Of note:

- TF is drafting the document, discussing with NA S23 Revision TF, and ESEC (Energy Saving Equipment Communications) TF under the I&C Committee.
- The document will be submitted for the earliest possible cycle, 2013.
- Supika Mashiro added the supplemental comments as follows:
  - ✓ ESEC (Energy Saving Equipment Communications) TF does not ask to EHS Committee to change the life Cycle itself. What we have discussed is to have some limitations when we applied the sleep mode. From their point of view, the sleep mode transition currently could occur from the maintenance mode, even the service mode.
  - Regarding the issue of the local competition with the host, the I&C Committee would only change it from the host online stage.

**Motion:** To submit Doc.#5513 for the earliest possible cycle.

By / 2<sup>nd</sup>: George Hoshi (Tokyo Electron) / Eiji Nakatani (SOKUDO)

**Discussion:** None.

**Vote:** 12 in favor and 0 opposed. **Motion passed.** 

**Action Item:** S23 Revision Task Force to submit Doc.#5513 for the earliest possible cycle.

**Attachment:** 04\_S23\_Rev\_TF\_Report\_121207

#### 7.5 FPD System Safety Task Force

Naokatsu Nishiguchi reported for the FPD System Safety Task Force. The Task Force currently has no activities.

#### 7.6 GHG Emission Characterization Task Force

George Hoshi reported on progress for the GHG Emission Characterization Task Force. Of note:

 The next meeting schedule for Friday, December 14, and the promotion and the practical use of SEMI S29 will be discussed.

# 7.7 Seismic Protection Task Force

Eiji Nakatani reported on the progress for the Seismic Protection Task Force. Of note:

 A new SNARF "Line Item Revisions to SEMI S2-0712, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment Revisions Related to Section 19 Seismic Protection" was presented to the committee for approval.

**Motion:** To approve a new SNARF for "Line Item Revisions to SEMI S2-0712"

By / 2<sup>nd</sup>: Eiji Nakatani (SOKUDO) / Naokatsu Nishiguchi (Dainippon Screen Manufacturing)

**Discussion:** • Chris Evanston suggested that it should be broaden flexibly to the other related standards, not only FEMA.

- Shigehito Ibuka asked what is related to the Facilities Committee.
  - > This section (Sec.19) is especially referred to equipment itself. TF thinks it needs to provide the document to the Facilities Committee and get their feedbacks.
- Supika Mashiro recommended to issue the inter-committee ballot to the PIC Committee as well as with the Facilities Committee, if the documents refers to the anchoring devices.

**Vote:** 4 in favor and 0 opposed. **Motion passed.** 

Attachment: 05\_Seismic\_Protection\_TF\_Report\_121207

06\_SNARF\_for\_Seismic\_Protection\_121207





### 7.8 STEP Planning Working Group

Moray Crawford reported for the STEP Planning Working Group. Of note:

STEP/SEMI S2 "EHS Guideline for Semiconductor Manufacturing Equipment" was held on November 22 at SEMI
Japan Tokyo Office. 89 attendees attracted and with kind support of all speakers and committee co-chairs, it was
closed successfully.

**Attachment:** 07\_STEP\_Planning\_WG\_Report\_121207

### 8 Old Business

#### 8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

### **Table 7 Previous Meeting Actions Items**

Item #	Assigned to	Details
EHS120419-05	STEP Planning Working Group	To hold STEP/ SEMI S2 in fall Close
EHS120419-06	SJ12 Program Planning Group	To hold a safety related program during SEMICON Japan 2012 Close
EHS120925-01	SEMI Staff	To forward adjudication result of Doc.#4976C to the ISC A&R Subcommittee for procedural review Close
EHS120925-02	SEMI Staff	To forward adjudication result of Doc.#5353 to the ISC A&R Subcommittee for procedural review Close
EHS120925-03	Seismic Protection Task Force	To submit SNARF at the next committee meeting Close

# 8.2 EHS Standards Program in conjunction with SEMICON Japan 2012

Hidtoshi Sakura reported for the EHS Standards program in conjunction with SEMICON Japan 2012. Of note:

• EHS Standards Program, "Trend of the Current Safety Demands -SEMI Safety Guidelines comparison with Major Safety Standards-", was successfully finished on December 5. 47 attendees participated and the lively and fruitful discussion was held, thanks to the speakers and the project group members.

**Attachment:** 08\_SJ12\_EHS\_Program\_Agenda\_121207

#### 9 New Business

None

#### 10 Action Item Review

10.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

# 11 Next Meeting and Adjournment

The next meeting of the Japan EHS Committee is scheduled for Thursday, April 18, 2013, 10:00-17:00 (Closing Time is TBD), at SEMI Japan, Tokyo, Japan.





Respectfully submitted by: Naoko Tejima Manager, Standards SEMI Japan

Phone: +81.3.3222.5804 Email: ntejima@semi.org

# Minutes approved by:

Supika Mashiro (Tokyo Electron), Co-chair	
Hidetoshi Sakura (Intel), Co-chair	January 18, 2013
Moray Crawford (Hatsuta Seisakusho), Co-chair	

# Table 8 Index of Available Attachments #1

#	Title	#	Title
1	JA_EHS_Previous_Mtg_Minutes_121207	5	Seismic_Protection_TF_Report_121207
2	SEMI_Staff_Report_121207	6	SNARF_for_Seismic_Protection_121207
3	NA_EHS_Report_December2012_121207	7	STEP_Planning_WG_Report_121207
4	S23_Rev_TF_Report_121207	8	SJ12_EHS_Program_Report_121207

<sup>#1</sup> Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.